

03500.015110.1



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Takako YAMAGUCHI et al.

Application No.: 10/630,792

Filed: July 31, 2003

For: PATTERN-FORMING APPARATUS
USING A PHOTOMASK (As Amended)

) Examiner: K. C. Gutierrez
:
:) Group Art Unit: 2851
:
:) Confirmation No.: 7876
:
:) Allowed: February 15, 2006
:
:) April 17, 2006
:

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application as follows: